



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Hideshi NISHIKAWA et al.) Art Unit: 1775
Serial No.: 10/809,712) Examiner: Speer, T.
Filed: March 26, 2004)

For: SILICON ANNEALED WAFER AND SILICON EPITAXIAL WAFER

AMENDMENT

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the outstanding Office Action dated July 18, 2006, please amend the application as follows: